

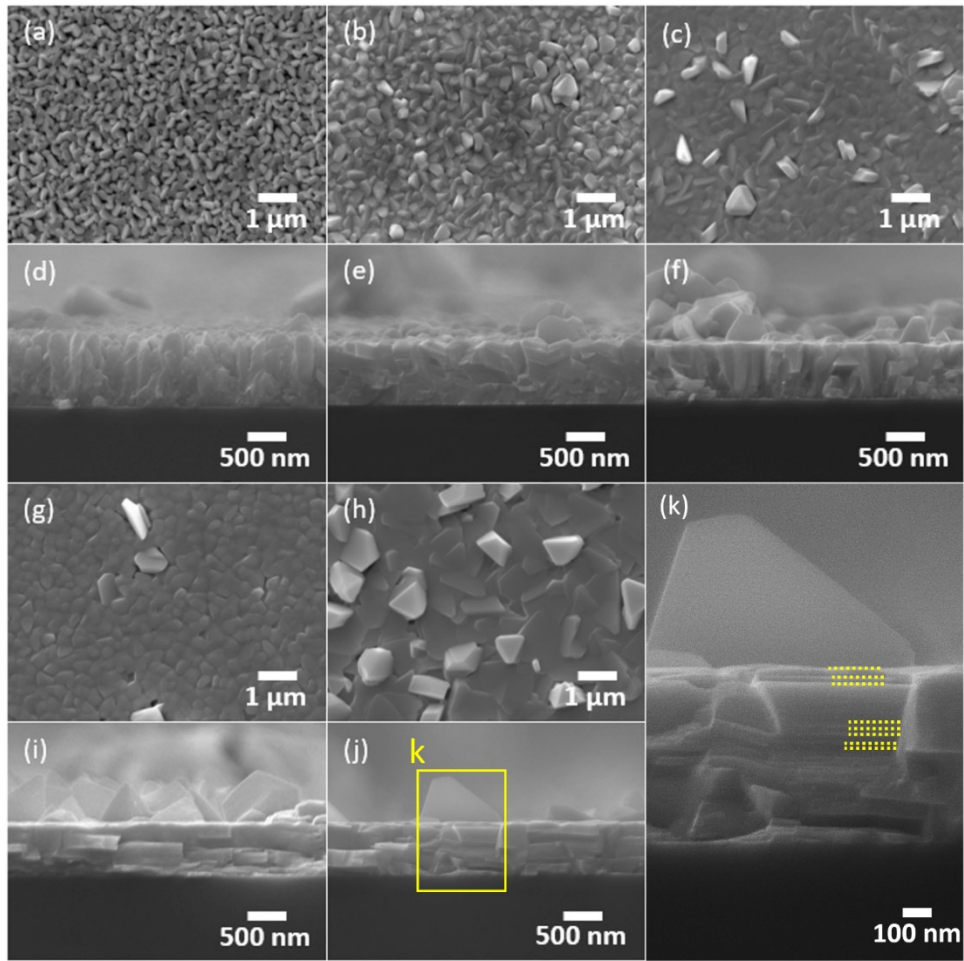
## Supporting Information

**Microstructure and transport modulation in Zn(Al)O-containing Bi<sub>2</sub>Te<sub>2.7</sub>Se<sub>0.3</sub> films**

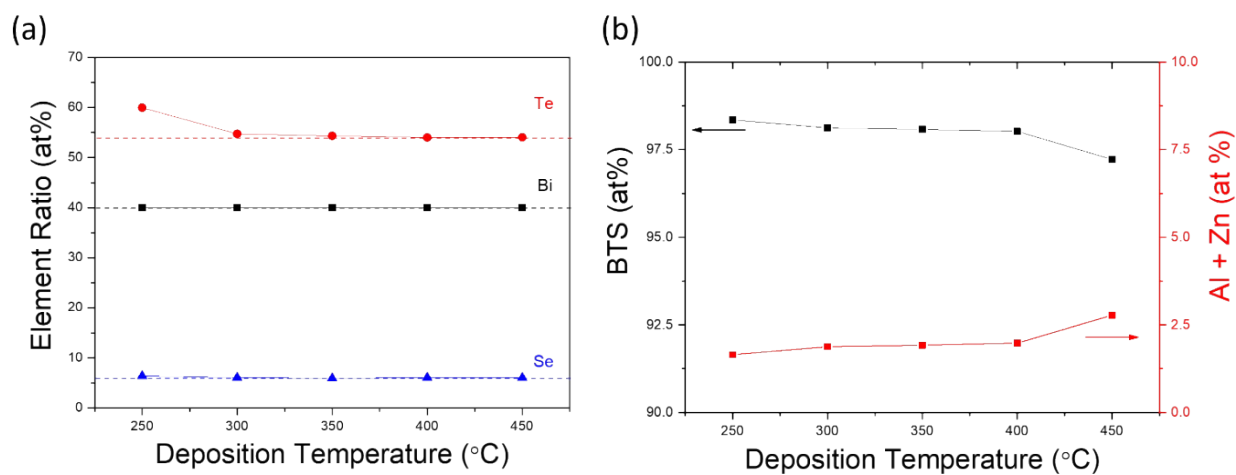
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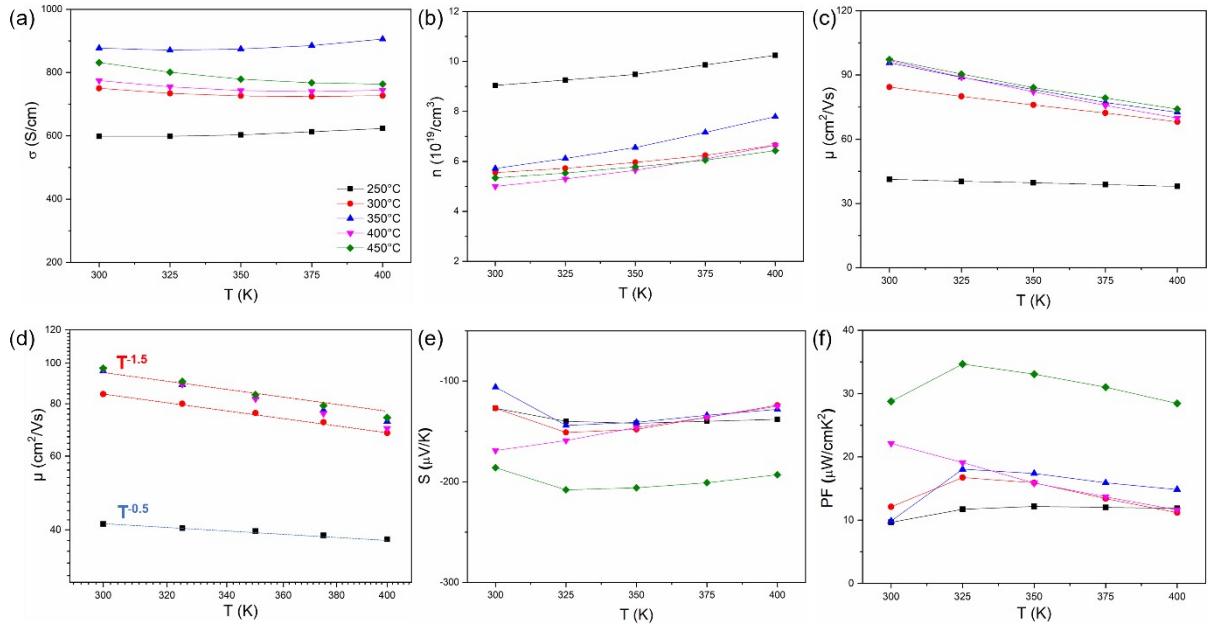
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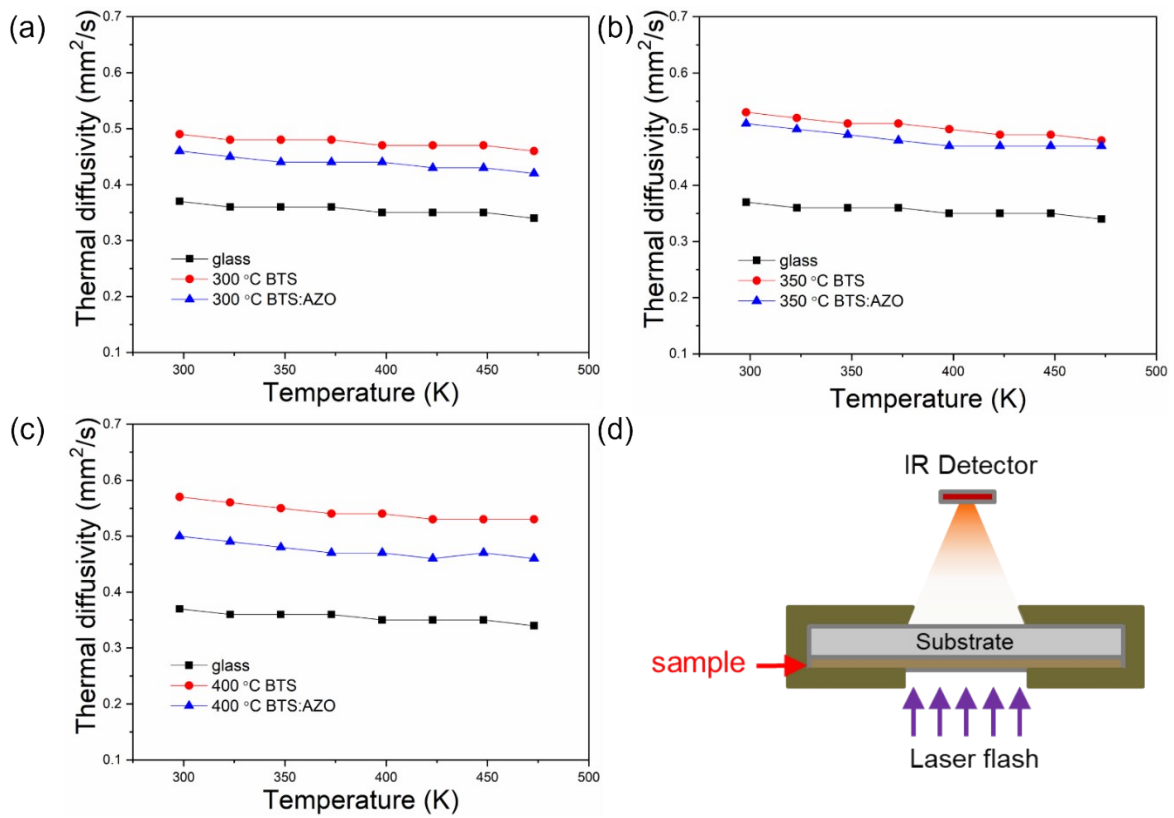
**Figure S1.** Top-view and cross-sectional SEM images of BTS films deposited at (a, d) 250 °C, (b, e) 300 °C, (c, f) 350 °C, (g, i) 400 °C, and (h, j) 450 °C. (k) Close-up image showing the periodic layered structure of the BTS:AZO films.



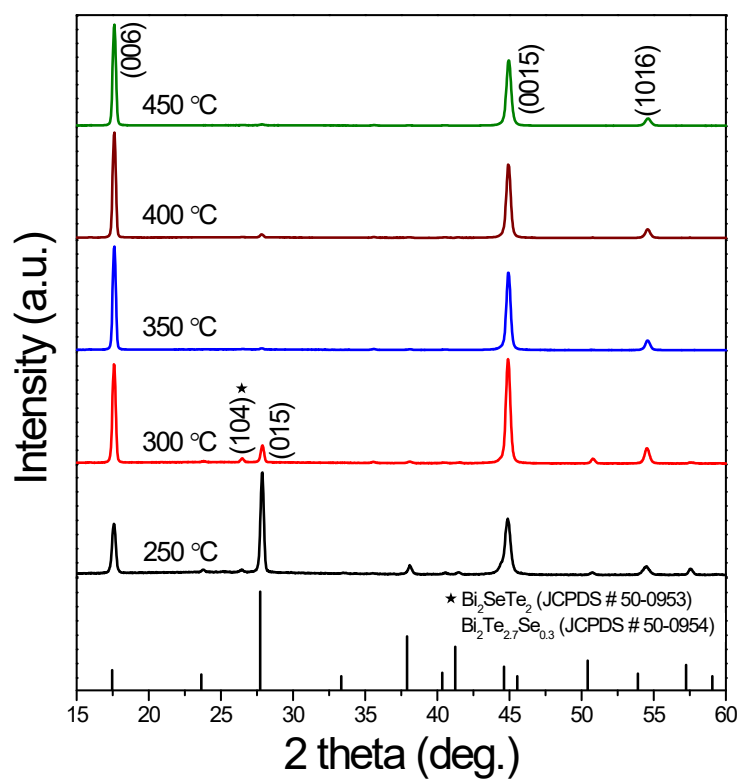
**Figure S2.** (a) Normalized composition ratios of Bi, Te, and Se, and (b) Normalized atomic fractions of the BTS-related elements (Bi + Te + Se) and (Al + Zn) as a function of deposition temperature..



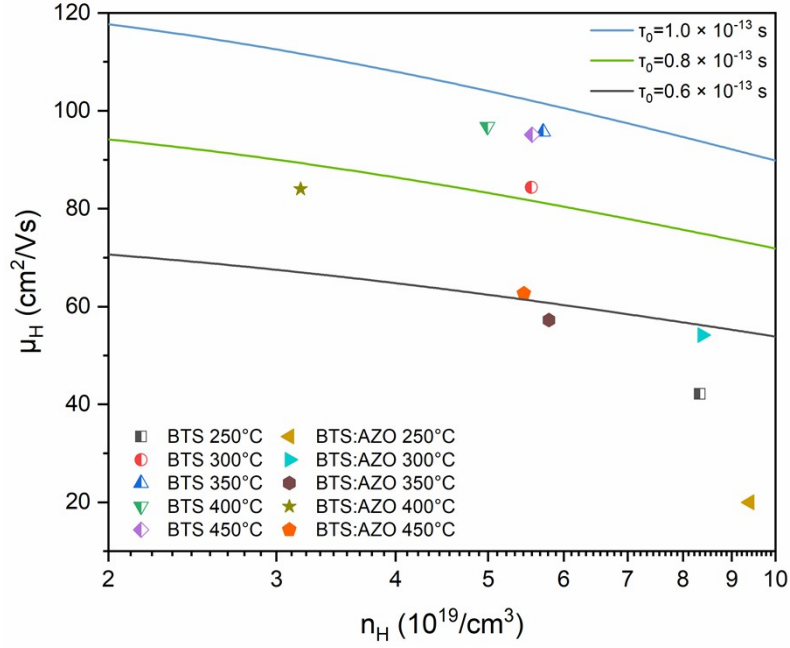
**Figure S3.** Temperature dependence of (a) electrical conductivity, (b) carrier concentration, (c) carrier mobility, (d) Log-log plot of mobility versus temperature, (e) Seebeck coefficient, and (f) power factor (PF) of the BTS films.



**Figure S4.** Thermal diffusion coefficients of the glass substrate, BTS, and BTS:AZO films deposited at (a) 300 °C, (b) 350 °C, and (c) 400 °C. (d) Schematic diagram of the thermal diffusion measurement setup.



**Figure S5.** XRD patterns of the BTS films deposited at various temperatures.

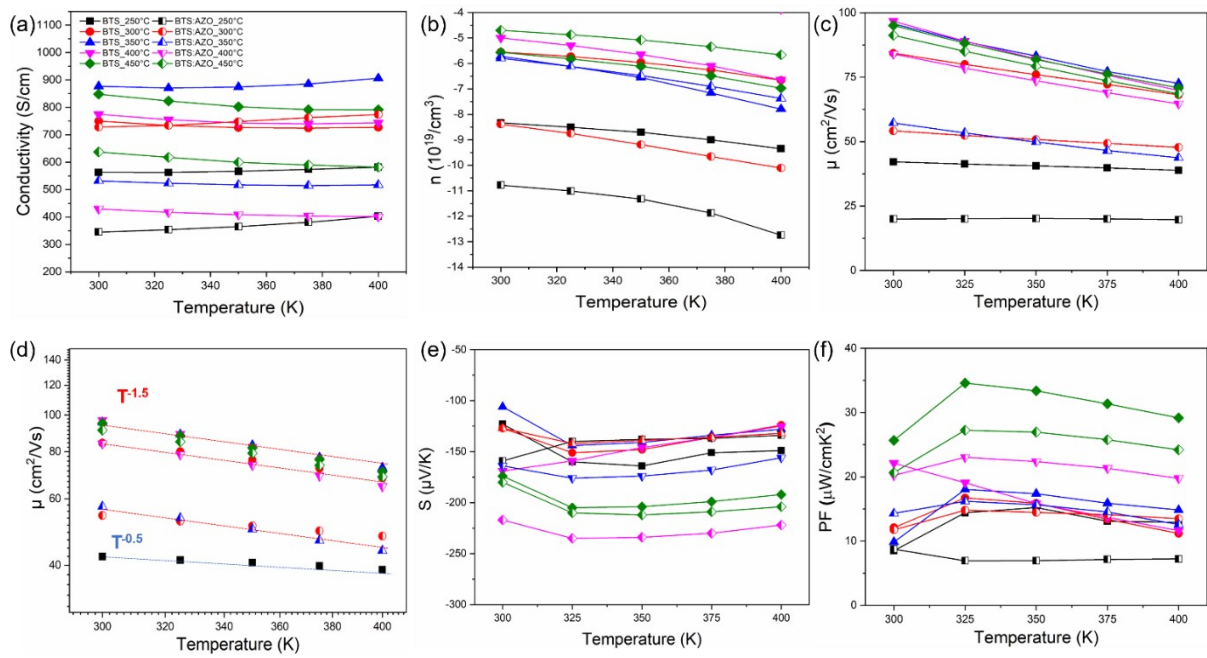


**Figure S6.** Carrier-density dependent carrier mobility at 300 K.

The carrier mobility ( $\mu$ ) depends on the conductive effective mass  $m_c^*$  and the average relaxation time ( $\tau$ ), which can be demonstrated by the following equations when acoustic phonon scattering dominates. Here, constant  $\tau_0$  is a  $n_H$ -independent relaxation time, and  $F_0$  and  $F_{1/2}$  are the Fermi integrals [1].

$$\mu = \frac{e(\tau)}{m_c^*} = \frac{2e\tau_0}{3m_c^*} \frac{F_0}{F_{1/2}} \quad (\text{Eq. 1})$$

The BTS:AZO films exhibit a relatively lower relaxation time ( $\tau_0$ ), suggesting more frequent carrier scattering. This result is likely due to the various defects introduced by the AZO doping, which increase the scattering events.



**Figure S7.** Temperature dependence of the (a) electrical conductivity, (b) carrier concentration, (c) carrier mobility, (d) mobility as a function of  $T^{-1}$ , (e) Seebeck coefficient, and (f) PF of the BTS and BTS:AZO films.

**Table S1.** Composition ratios of Bi, Te, and Se, and AZO doping concentrations in the BTS:AZO films deposited at various deposition temperatures.

BTS:AZO	at%			
	Bi	Te	Se	Te/Bi
250 °C	37.56	56.29	6.15	1.5
300 °C	39.67	54.32	6.01	1.48
350 °C	39.88	54.18	5.94	1.35
400 °C	39.97	53.97	6.06	1.35
450 °C	39.95	54.01	6.04	1.35

BTS:AZO	at%		
	Al	Zn	BTS
250 °C	0.54	1.11	98.35
300 °C	1.00	0.88	98.12
350 °C	0.84	1.08	98.08
400 °C	1.13	0.85	98.02
450 °C	1.06	1.72	97.22

**Table S2.** Lattice constants of the BTS and BTS:AZO films deposited at various temperatures.

Sample	BTS		BTS:AZO	
	a=b (Å)	c (Å)	a=b (Å)	c (Å)
250 °C	4.36	30.25	4.36	30.27
300 °C	4.36	30.25	4.35	30.29
350 °C	4.36	30.21	4.36	30.24
400 °C	4.36	30.21	4.36	30.26
450 °C	4.37	30.20	4.35	30.23

**Table S3.** The full width at half maximum of the (006) diffraction peak and the grain size of the BTS and BTS:AZO films.

Sample	BTS		BTS:AZO	
	FWHM (°)	Grain size (nm)	FWHM (°)	Grain size (nm)
250 °C	0.286	29.1	0.271	30.7
300 °C	0.254	32.8	0.308	27.1
350 °C	0.246	33.9	0.258	32.4
400 °C	0.246	33.9	0.256	32.6
450 °C	0.249	33.5	0.249	33.5

**Table S4.** Thickness comparison between the BTS and BTS:AZO films

TD (°C)	Sample	Thickness
250	BTS	1153
	BTS:AZO	1003
300	BTS	890
	BTS:AZO	880
350	BTS	827
	BTS:AZO	773
400	BTS	789
	BTS:AZO	753
450	BTS	741
	BTS:AZO	719

**Table S5.** Comparison of the thermoelectric properties of Bi<sub>2</sub>Te<sub>2.7</sub>Se<sub>0.3</sub>-based films with different compositions and modifications.

Composition	S ( $\mu\text{V/K}$ )	PF ( $\mu\text{W/cmK}^2$ )	$\kappa$ (W/mK)	zT	Year, Ref
Bi <sub>2</sub> Te <sub>2.7</sub> Se <sub>0.3</sub>	-180	12	-	-	2010 [2]
Pt <sub>0.060</sub> /Bi <sub>2</sub> Te <sub>2.7</sub> Se <sub>0.3</sub>	-200	35	0.86	1.17	2014 [3]
Bi <sub>2</sub> Te <sub>2.7</sub> Se <sub>0.3</sub>	-190	18	0.65	0.9	2017 [4]
Bi <sub>2</sub> Te <sub>2.7</sub> Se <sub>0.3</sub>	-240	45	-	1.6	2019 [5]
BTS-2Cu/Ni	-200	29.8	0.93	0.97	2020 [6]
Bi <sub>2</sub> Te <sub>3</sub> /Te	-160	14.6	-	-	2021 [7]
Bi <sub>2</sub> Te <sub>3</sub>	-180	47	-	-	2021 [8]
(CuI) <sub>0.002</sub> Bi <sub>2</sub> Te <sub>2.7</sub> Se <sub>0.3</sub>	-180	63.5	1.5	1.42	2022 [9]
ZnO/BTS	-210	33.5	0.81	1.25	2024 [10]
Bi <sub>2</sub> Te <sub>2.7</sub> Se <sub>0.3</sub>	-155	35.1	1.01	1.14	2026 [11]

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